เอกสารอ้างอิง

1. Statistical Forecasting Bureau, 2007, "The Disability", **The 2007 Disability Survey Report**., National Statistical Office, pp. 2-15.

2. Soo, H.E., Hoon, S.J. and Jun, K.Y., 2007, "A Polymer-Based Flexible Tactile Sensor for Both Normal and Shear Load Detections and Its Application for Robotics", **Journal of Microelectromechanical Systems**., Vol. 16, pp. 556-563.

3. Soo, H.E. and Jun, K.Y., 2007, "A Polymer-based Flexible Tactile Sensor and Its Application to Robotics", **IEEE SENSORS Conference**, 28-31 Oct 2007, Atlanta USA, pp. 784-787.

4. Beliveau, A., Spencer, G.T., Thomas, K.A. and Roberson, S.L., 1999, "Evaluation of MEMS capacitive accelerometers", **IEEE Design & Test of Computers,** Vol. 16, pp. 48-56.

5. Haque, M.A. and Saif, M.T.A., 2002, "Application of MEMS force sensors for in situ mechanical characterization of nano-scale thin films in SEM and TEM", **Sensors and Actuators A: Physical**, Vol. 97–98, pp. 239-245.

6. Ho, K.J., Chang, C.W., Joon, K.H. and Im, K.D., 2006, "Development of tactile sensor with functions of contact force and thermal sensing for attachment to intelligent robot finger tip", **Conference on IEEE SENSORS 2006**, pp. 1468-1472.

7. Schmidt, M.A., Howe, R.T., Senturia, S.D. and Haritonidis, J. H., 1988, "Design and calibration of a microfabricated floating-element shear-stress sensor", **IEEE Transactions on Electron Devices**, Vol. 35, pp. 750-757.

8. Shajii, J., Ng, K.Y. and Schmidt, M.A., 1992, "A microfabricated floating-element shear stress sensor using wafer-bonding technology", **Journal of Microelectromechanical Systems**, Vol. 1, pp. 89-94.

9. Yang, M. and Thompson, M., 1993, "Multiple chemical information from the thickness shear mode acoustic wave sensor in the liquid phase", **Analytical Chemistry**, 1 May 1993, Vol. 65, pp. 1158-1168.

10. Fukang, J., Chong, T.Y., Walsh, K., Tsao, T., Bin, L.G. and Ming, H.C., 1997, "A flexible MEMS technology and its first application to shear stress sensor skin", **Annual International Workshop on IEEE International Conference Micro Electro Mechanical Systems**, 26-30 Jan 1997, Nagoya Japan, pp. 465-470.

11. Chang, L., Biao, H.J., Zhenjun, Z., Fukang, J., Tung, S., Chong, T.Y. and Ming, H.C., 1999, "A micxromachined flow shear-stress sensor based on thermal transfer principles," **Journal of Microelectromechanical Systems**, Vol. 8, pp. 90-99.

12. Jiang, Z., Farmer, K.R. and Modi, V., 2001, "A MEMS device for measurement of skin friction with capacitive sensing", **IEEE International Conference Micro Electro Mechanical Systems. MEMS 2001**, 24-26 Aug 2001, pp. 4-7.

13. Xu, Y., Jiang, F., Newbern, S., Huang, A., Ming, H.C. and Chong, T.Y., 2003, "Flexible shear-stress sensor skin and its application to unmanned aerial vehicles", **Sensors and Actuators A: Physical**, Vol. 105, 15 Jul 2003, pp. 321-329.

14. Sundara-Rajan, K., Rowe, G.I., Simon, A.J., Klute, G.K., Ledoux, W.R. and Mamishev, A.V., 2009, "Shear sensor for lower limb prosthetic applications", **Biomedical Science & Engineering Conference (BSEC 2009) First Annual ORNL**, 18-19 Mar 2009, Oak Ridge, Tennessee, pp. 1-4.

15. Murdock, D., 2008, "Capacitance and Dielectrics", in **Worked Examples from Introductory Physics Vol. IV: Electric Fields**. Vol. 4, Tennessee Tech University, pp. 71-85.

16. Leus, V. and Elata, D., 2004, "Fringing field effect in electrostatic actuators", in **Technical Repor ETR**, Technion Israel Institute of Technology, pp. 3 - 45.

17. Beer, F.P., Johnston J.E.R. and Dewolf, J.T., 2006, "Introduction-Concepts of Stress, Stress and Strain-Axial Loading", in **Mechanics of Materials**, 4th ed., McGraw-Hill, Singapore, pp. 5-98.

18. Rowe, G.I. and Mamishev, A.V., 2004, "Simulation of a sensor array for multiparameter measurements at the prosthetic limb interface", **Health Monitoring and Smart Nondestructive Evaluation of Structural and Biological Systems.**, 14 Mar 2004, San Diego California, pp. 493-500.

19. Armani, D., Liu, C. and Aluru, N., 1999, "Re-configurable fluid circuits by PDMS elastomer micromachining", **IEEE International Conference on Micro Electro Mechanical Systems, (MEMS '99)**., 17-21 Jul 1999, Orlando Florida USA, pp. 222-227.

20. Dow Corning, 2013, **Sylgard® 184 Silicone Elastomer KIT** [Online], Available: http://www.dowcorning.com/applications/search/default.aspx?R=131EN [2 Nov 2012]

21. DuPont Teijin Films, 2003, " Typical Electrical Properties of Mylar Polyester Film", in **Product Information Mylar® polyester film**, DuPont Teijin Films, USA, pp.2-8.

22. Institute of FIeld roBOtics, 2012, "HANUMAN KMUTT TEAM HUMANOID", in **Technical Report,** King Mongkut's University of Technology Thonburi, pp.1-2.